



Docket No.: 9323.050.00-US  
(PATENT)

**IN THE UNITED STATES PATENT AND TRADEMARK OFFICE**

In re Patent Application of:

In-Kwon Jeong

Confirmation No.: 1220

Application No.: 09/917,344

Group Art Unit: 1763

Filed: July 27, 2001

Examiner: Macarthur, S.

For: CMP SYSTEM AND METHOD FOR  
EFFICIENTLY PROCESSING  
SEMICONDUCTOR WAFERS

Customer No.: 30827

**AMENDMENT**

Mail Stop Amendment  
Commissioner for Patents  
Alexandria, VA 22313-1450

Dear Sir:

In response to the Office Action dated March 14, 2006, please amend the above-identified application as follows:

**Amendments to the Claims** are reflected in the listing of claims which begins on page **2** of this paper.

**Remarks** begin on page **20** of this paper.